

ABSTRACT

5 A conductive film is formed on a substrate into
which a MEMS circuit is fabricated, and a film of a
dielectric A having a low dielectric constant and a film
of a dielectric B having a high dielectric constant are
formed on the conductive film, followed by the formation
of a conductive film over the dielectric films. A
millimeter wave is guided along the film of the
10 dielectric B functioning as a dielectric waveguide, and
is propagated along its length while being reflected by
the conductors.